## BOX AF





## RESPONSE UNDER 37 C.F.R. § 1.116 EXPEDITED PROCEDURE REQUESTED EXAMINING GROUP 2823

PATENT Customer No. 22,852 Attorney Docket No. 04329.2622

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re A	application of:	)
Gaku MINAMIHABA, et al.		) Group Art Unit: 2823
Serial No.: 09/932,943		Examiner: Lee, Hsien Ming
Filed:	August 21, 2001	) )
For:	SLURRY FOR CHEMICAL MECHANICAL POLISHING AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE	) ) )
Comm P.O. B	Stop AF hissioner for Patents sox 1450 hdria, VA 22313-1450	
Sir:		

## PETITION FOR EXTENSION OF TIME

Applicants hereby petition for a two-month extension of time to reply to the Final Office Action mailed September 16, 2004. A fee of \$450 is enclosed.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

02/10/2005 SDENBOB1 00000054 09932943

01 FC:1252

450.00 BP

FINNEGAN, HENDERSON, FARABOW, GARRETT & DUNNER, L.L.P.

Dated: February 9, 2005

David M. Longo Reg. No. 53,235